

The PUR-X replaceable tube circulation heater provides contamination-free heating of liquids and gases.

APPLICATIONS

- Semiconductor solvent heating
- High-purity liquid heating

SPECIFICATIONS

- PUR-X 1000: 1.5kW – 4.5kW, 120V, 200V, 208V, 220V, 230V, 240V, 380V, 400V, 415V
- Explosion Resistant (NEMA 7) electrical enclosure
- Tubing, .375" (3/8") O.D. x .031" wall, field replaceable
 - Standard PFA
 - High Purity PFA, compliant with SEMI F57
 - 190" Long (15.8 ft or 4.8 m)
 - Tube size & length are the same for both standard
 - PFA & high purity PFA
- Body: Aluminum 319, Teflon®-coated
- Maximum operating temperature: 200°C (392°F)
- Two sensors, for process control and process high-limit, choice of J or K type thermocouples
- Third sensor (J or K type, matching the selected process sensors) for casting and tube protection. Requires independent high limit control loop set no higher than 235° C. (455° F)
- Optional insulation jacket
- Optional fittings, PFA 3/8" Straight Union, Semi F57 compliant
- 70 psi max (480 kPa)
- Size and weight:
 - PUR-X 1000: 4.3" O.D. (10.9cm) x 16.5" (41.9 cm) tall,
 - 22 lbs (9.9 Kg) (includes housing)



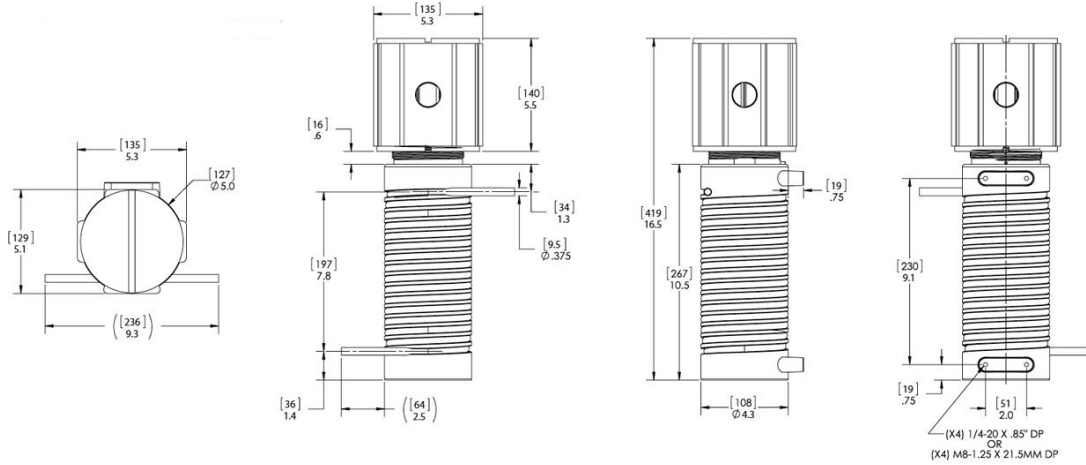
FEATURES/BENEFITS

- Heating elements cast in aluminum
- Low maintenance
- Teflon®- coated for easy cleaning
- High purity heating
- Fluid path independent of heater sheath
- Non-welded construction
- Self-draining with replaceable tubing

APPLICATIONS

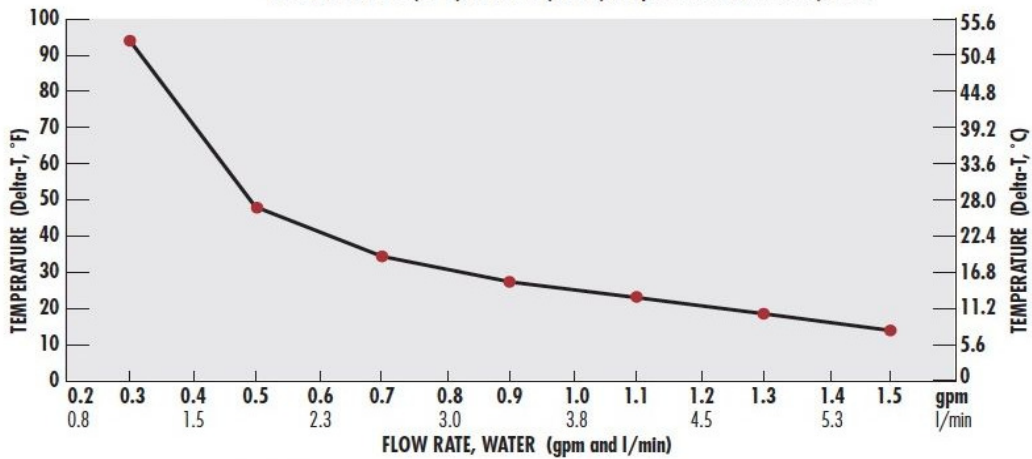
- Semiconductor wet process systems
- Wafer cleaning equipment (wet bench systems)
- Heating of photo-resist removal solvents
- DI water heating for wafer rinsing
- Air and Nitrogen heating for wafer drying
- Acid heating

TECHNICAL DRAWING

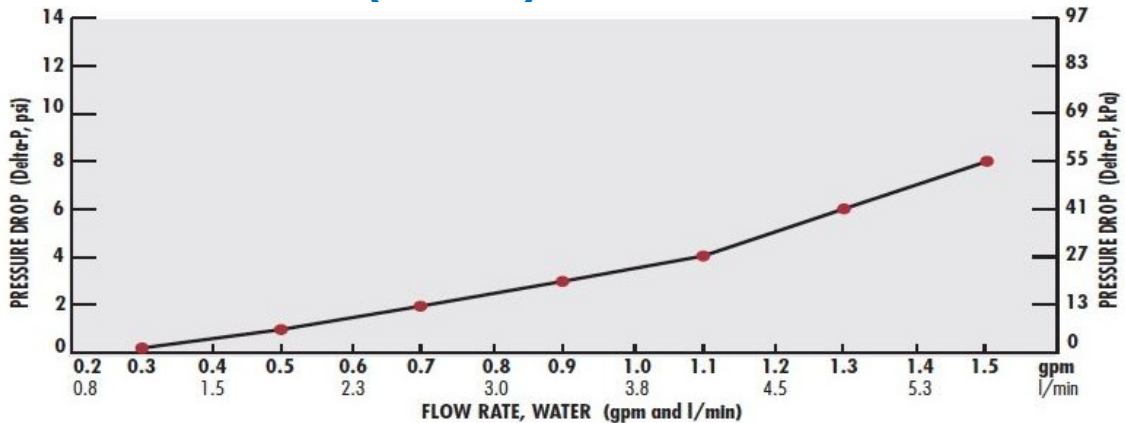


HEATING PROFILE (WATER)

Inlet water 15°C (59°F) at 200°C (392°F) set point with insulation jacket.

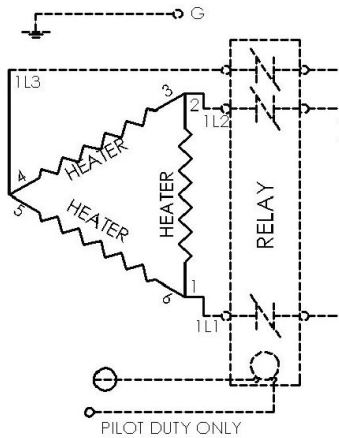


PRESSURE DROP PROFILE (WATER)

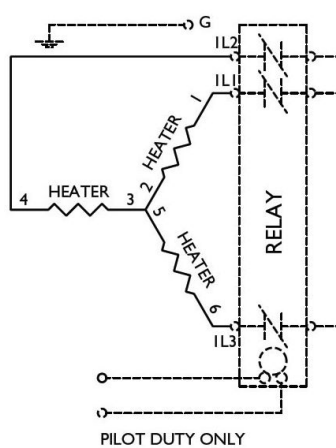


WIRING DIAGRAMS

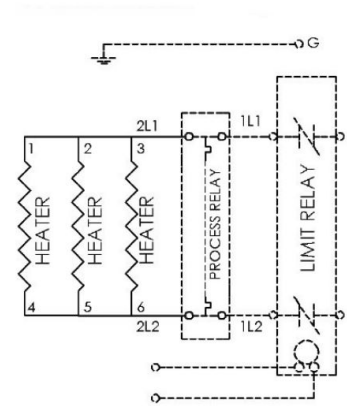
3-Phase Delta



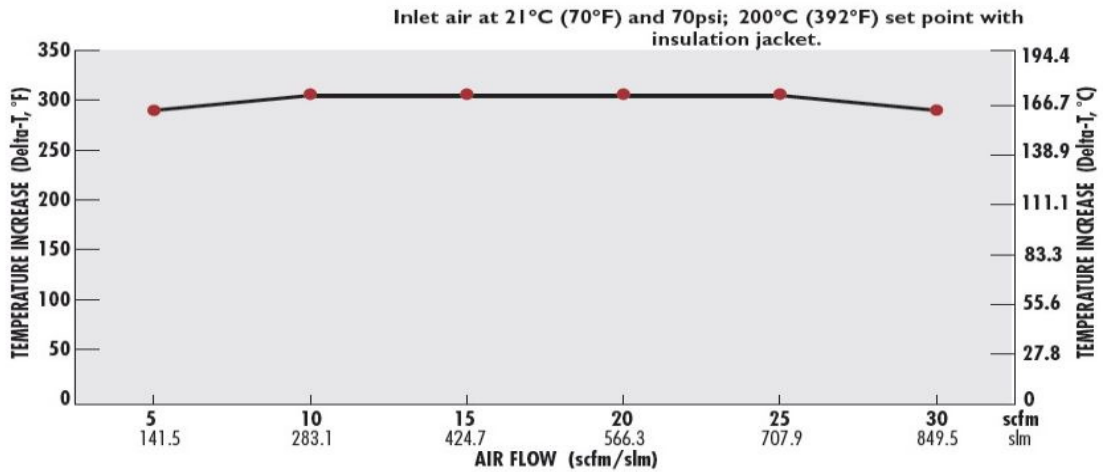
3-Phase Wye



1-Phase Circuit



HEATING PROFILE (AIR)



PRESSURE DROP (AIR)

